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... and returns the scattered and the reflected **beams** to the **photodetector**. ... **Particle Size**
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generates the **laser beams** needed for one-, two- or three-compo-. nent PDPA/LDV
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Average Diameter Arithmetic average of **particle size** - micrometers ...
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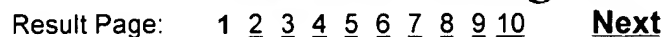The distance along the **laserbeam**, where crossing **particles** produce a ...
w3.gkss.de/Pms/probes1.htm - 16k - Cached - Similar pages

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Fluctuations in the light **beam** are measured by the **photodetector**. **Particles** in the sample

stream cross the **laser beam** blocking a portion of the light, ...
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20Counters-article.doc - <u>Similar pages</u>

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Therefore, a signal which has a weaker **particle size** dependence can allow access ... A
laser beam is split by a beamsplitter into two perpendicular paths. ...
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Last Name = MORIYA
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Application#	Patent#	Status	Date Filed	Title	Inventor Name
09273293	6306770	150	03/19/1999	METHOD AND APPARATUS FOR PLASMA ETCHING	MORIYA, TSUYOSHI
09290636	6184489	150	04/12/1999	PARTICLE-REMOVING APPARATUS FOR A SEMICONDUCTOR DEVICE MANUFACTURING APPARATUS AND METHOD OF REMOVING PARTICLES	MORIYA, TSUYOSHI
09413590	6115120	150	10/06/1999	SYSTEM AND METHOD FOR DETECTING PARTICLES PRODUCED IN A PROCESS CHAMBER BY SCATTERING LIGHT	MORIYA, TSUYOSHI
09443050	Not Issued	164	11/18/1999	PARTICLE DETECTION SYSTEM AND METHOD USING MONITORED OPERATING CONDITIONS OF A PROCESS CHAMBER	MORIYA, TSUYOSHI
09651186	6346425	150	08/30/2000	Vapor-phase processing method capable of eliminating particle formation	MORIYA, TSUYOSHI
09656713	Not Issued	71	09/07/2000	Apparatus for monitoring particles and method of doing the same	MORIYA, TSUYOSHI
09685351	6423176	150	10/10/2000	PARTICLE-REMOVING APPARATUS FOR A SEMICONDUCTOR DEVICE MANUFACTURING APPARATUS AND METHOD OF REMOVING PARTICLES	MORIYA, TSUYOSHI
09721703	6737666	150	11/27/2000	APPARATUS AND METHOD FOR DETECTING AN END POINT OF A CLEANING PROCESS	MORIYA, TSUYOSHI

09767960	Not Issued	161	01/24/2001	Dust particle removing method and apparatus, impurity detecting method and system	MORIYA, TSUYOSHI
09950759	Not Issued	161	09/13/2001	Semiconductor fabrication device and method for preventing the attachment of extraneous particles	MORIYA, TSUYOSHI
09962169	Not Issued	161	09/24/2001	Semiconductor device manufacturing apparatus and method for manufacturing a semiconductor device	MORIYA, TSUYOSHI
09971463	Not Issued	83	10/05/2001	Particle-removing apparatus for a semiconductor device manufacturing apparatus and method of removing particles	MORIYA, TSUYOSHI
10166303	Not Issued	71	06/11/2002	Method of manufacturing semiconductor devices and semiconductor manufacturing apparatus	MORIYA, TSUYOSHI
10722602	Not Issued	30	11/28/2003	Internal member of a plasma processing vessel	MORIYA, TSUYOSHI
10773245	Not Issued	30	02/09/2004	Plasma processing apparatus, ring member and plasma processing method	MORIYA, TSUYOSHI
10858049	Not Issued	30	06/02/2004	Substrate processing apparatus and substrate transferring method	MORIYA, TSUYOSHI
10920367	Not Issued	30	08/18/2004	Particle removal apparatus and method and plasma processing apparatus	MORIYA, TSUYOSHI
10921947	Not Issued	30	08/20/2004	Method for cleaning elements in vacuum chamber and apparatus for processing substrates	MORIYA, TSUYOSHI
10959197	Not Issued	30	10/07/2004	Particle sticking prevention apparatus and plasma processing apparatus	MORIYA, TSUYOSHI
11065359	Not Issued	20	02/25/2005	Processing apparatus and method for removing particles therefrom	MORIYA, TSUYOSHI
11091416	Not Issued	20	03/29/2005	Plasma processing apparatus and method	MORIYA, TSUYOSHI
11091417	Not Issued	20	03/29/2005	Vacuum apparatus including a particle monitoring unit, particle monitoring method and program, and window member for use in the particle monitoring	MORIYA, TSUYOSHI

11115357	Not Issued	19	04/27/2005	Substrate transfer device and cleaning method thereof and substrate processing system and cleaning method thereof	MORIYA, TSUYOSHI
11115358	Not Issued	30	04/27/2005	Substrate cleaning apparatus and method	MORIYA, TSUYOSHI
11128256	Not Issued	20	05/13/2005	Substrate transfer mechanism and subtrate transfer apparatus including same, particle removal method for the subtrate transfer mechanism and apparatus, program for executing the method, and storage medium for storing the program	MORIYA, TSUYOSHI
11171236	Not Issued	20	07/01/2005	Apparatus for inspecting a surface of an object to be processed	MORIYA, TSUYOSHI
60589807	Not Issued	159	07/22/2004	Transfer apparatus and processing system of workpieces and method thereof	MORIYA, TSUYOSHI
60589808	Not Issued	159	07/22/2004	Method and apparatus for cleaning workpieces	MORIYA, TSUYOSHI
60589810	Not Issued	159	07/22/2004	Particle monitor and processing system with particle monitor	MORIYA, TSUYOSHI
60598425	Not Issued	159	08/04/2004	Apparatus for inspecting surface of workpiece	MORIYA, TSUYOSHI
60626467	Not Issued	20	11/10/2004	Apparatus for plasma processing, and method, computer program and recording medium	MORIYA, TSUYOSHI
60635615	Not Issued	20	12/14/2004	Method, apparatus, computer program and recording medium for cleaning substrate, and system for processing substrate	MORIYA, TSUYOSHI
60635617	Not Issued	20	12/14/2004	Vacuum apparatus, method for particle monitor thereof, computer program for the method and window member for particle monitor	MORIYA, TSUYOSHI
60635942	Not Issued	20	12/15/2004	System and apparatus for transferring substrate, method for removing particle thereof, computer program for the method and recording medium for the computer program	MORIYA, TSUYOSHI
60635945	Not Issued	20	12/15/2004	Controlling method for substrate-processing apparatus, substrate-	MORIYA, TSUYOSHI

				processing apparatus, computer program for the method	
60635968	Not Issued	20	12/15/2004	Member for substrate processing apparatus and method for making the same	MORIYA, TSUYOSHI
60635970	Not Issued	20	12/15/2004	Ceramic-sprayed member, method for cleaning the same, computer program for the method and recording medium for the computer program	MORIYA, TSUYOSHI
60650956	Not Issued	20	02/09/2005	Cleaning method of processing apparatus, computer program for performing the method, and recording medium for storing the program	MORIYA, TSUYOSHI
60662794	Not Issued	20	03/18/2005	Member for introducing gas and plasma processing apparatus using the same	MORIYA, TSUYOSHI
60663187	Not Issued	20	03/21/2005	Reflection device, manifold and vacuum pump for exhausting gas, and exhaust system therewith	MORIYA, TSUYOSHI
60666703	Not Issued	20	03/31/2005	Atmospheric transfer module	MORIYA, TSUYOSHI
60666717	Not Issued	20	03/31/2005	Method of removing moisture from vacuum vessel, computer program of executing the method and storage medium of the program	MORIYA, TSUYOSHI
08680863	5889596	150	07/16/1996	CONTROLLING A READING UNIT OF AN IMAGE PROCESSING APPARATUS	MORIYAMA, TSUYOSHI
08843271	6094510	150	04/14/1997	IMAGE PROCESSING APPARATUS AND METHOD FOR PREDICTING A COMPRESSION RATE OF IMAGE DATA PROCESSED TO MODIFY AN IMAGE	MORIYAMA, TSUYOSHI
09092091	6413884	150	06/05/1998	METHOD OF PRODUCING THIN FILMS USING CURRENT OF PROCESS GAS AND INERT GAS COLLIDING WITH EACH OTHER	MORIYAMA, TSUYOSHI
09261955	6337970	150	03/03/1999	IMAGE FORMING APPARATUS HAVING SHEET PROCESSOR	MORIYAMA, TSUYOSHI
09282489	6391116	150	03/31/1999	SEMICONDUCTOR DEVICE	MORIYAMA,

				MANUFACTURING APPARATUS AND SEMICONDUCTOR DEVICE MANUFACTURING METHOD	TSUYOSHI
09418590	6263173	150	10/15/1999	Image formation apparatus having selection of different image types for image formation	MORIYAMA, TSUYOSHI
09438525	6219503	150	11/12/1999	SHEET PROCESSING APPARATUS AND METHOD WITH MULTI-MODE SHEET CONVEYING	MORIYAMA, TSUYOSHI
09438527	6386080	150	11/12/1999	SHEET PROCESSOR THAT ADJUSTS A PUNCHING OPERATION POSITION BASED ON A DETECTED SHEET EDGE AND ASSOCIATED IMAGE FORMING APPARATUS	MORIYAMA, TSUYOSHI

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Last Name = ITO
First Name = NATSUKO

Application#	Patent#	Status	Date Filed	Title	Inventor Name
08252656	Not Issued	161	06/01/1994	ACCELERATION SENSOR	ITO, NATSUKO
08541266	5747991	150	10/12/1995	CAPACITANCE TYPE ACCELERATION SENSOR	ITO, NATSUKO
08837942	5870189	150	04/28/1997	PARTICLE MONITOR AND PARTICLE-FREE RECESSING SYSTEM WITH PARTICLE MONITOR	ITO, NATSUKO
08989630	5861951	150	12/12/1997	PARTICLE MONITORING INSTRUMENT	ITO, NATSUKO
09070750	6042650	150	05/01/1998	PROCESSING APPARATUS FOR FABRICATING LSI WITH PROTECTED BEAM DAMPER	ITO, NATSUKO
09273293	6306770	150	03/19/1999	METHOD AND APPARATUS FOR PLASMA ETCHING	ITO, NATSUKO
09290636	6184489	150	04/12/1999	PARTICLE-REMOVING APPARATUS FOR A SEMICONDUCTOR DEVICE MANUFACTURING APPARATUS AND METHOD OF REMOVING PARTICLES	ITO, NATSUKO
09413590	6115120	150	10/06/1999	SYSTEM AND METHOD FOR DETECTING PARTICLES PRODUCED IN A PROCESS CHAMBER BY SCATTERING LIGHT	ITO, NATSUKO
09443050	Not Issued	164	11/18/1999	PARTICLE DETECTION SYSTEM AND METHOD USING MONITORED OPERATING CONDITIONS OF A PROCESS CHAMBER	ITO, NATSUKO
09504435	6284049	150	02/15/2000	Processing APPARATUS FOR FABRICATING LSI DEVICES	ITO, NATSUKO

09651186	6346425	150	08/30/2000	Vapor-phase processing method capable of eliminating particle formation	ITO, NATSUKO
09656713	Not Issued	71	09/07/2000	Apparatus for monitoring particles and method of doing the same	ITO, NATSUKO
09685351	6423176	150	10/10/2000	PARTICLE-REMOVING APPARATUS FOR A SEMICONDUCTOR DEVICE MANUFACTURING APPARATUS AND METHOD OF REMOVING PARTICLES	ITO, NATSUKO
09721703	6737666	150	11/27/2000	APPARATUS AND METHOD FOR DETECTING AN END POINT OF A CLEANING PROCESS	ITO, NATSUKO
09767960	Not Issued	161	01/24/2001	Dust particle removing method and apparatus, impurity detecting method and system	ITO, NATSUKO
09950759	Not Issued	161	09/13/2001	Semiconductor fabrication device and method for preventing the attachment of extraneous particles	ITO, NATSUKO
09962169	Not Issued	161	09/24/2001	Semiconductor device manufacturing apparatus and method for manufacturing a semiconductor device	ITO, NATSUKO
09971463	Not Issued	83	10/05/2001	Particle-removing apparatus for a semiconductor device manufacturing apparatus and method of removing particles	ITO, NATSUKO
10166303	Not Issued	71	06/11/2002	Method of manufacturing semiconductor devices and semiconductor manufacturing apparatus	ITO, NATSUKO
09236593	Not Issued	161	01/26/1999	PHARMACEUTICAL COMPOSITIONS FOR THE TREATMENT OF ISCHEMIC BRAIN DAMAGE	ITOH, NATSUKO

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Your Search was:

Last Name = UESUGI
First Name = FUMIHIKO

Application#	Patent#	Status	Date Filed	Title	Inventor Name
07123460	4873413	150	11/20/1987	METHOD AND APPARATUS FOR WRITING A LINE ON A PATTERNED SUBSTRATE	UESUGI, FUMIHIKO
07717603	5393577	150	06/19/1991	METHOD FOR FORMING A PATTERNED LAYER BY SELECTIVE CHEMICAL VAPOR DEPOSITION	UESUGI, FUMIHIKO
08837942	5870189	150	04/28/1997	PARTICLE MONITOR AND PARTICLE-FREE RECESSING SYSTEM WITH PARTICLE MONITOR	UESUGI, FUMIHIKO
08989630	5861951	150	12/12/1997	PARTICLE MONITORING INSTRUMENT	UESUGI, FUMIHIKO
09070750	6042650	150	05/01/1998	PROCESSING APPARATUS FOR FABRICATING LSI WITH PROTECTED BEAM DAMPER	UESUGI, FUMIHIKO
09273293	6306770	150	03/19/1999	METHOD AND APPARATUS FOR PLASMA ETCHING	UESUGI, FUMIHIKO
09290636	6184489	150	04/12/1999	PARTICLE-REMOVING APPARATUS FOR A SEMICONDUCTOR DEVICE MANUFACTURING APPARATUS AND METHOD OF REMOVING PARTICLES	UESUGI, FUMIHIKO
09413590	6115120	150	10/06/1999	SYSTEM AND METHOD FOR DETECTING PARTICLES PRODUCED IN A PROCESS CHAMBER BY SCATTERING LIGHT	UESUGI, FUMIHIKO
09443050	Not Issued	164	11/18/1999	PARTICLE DETECTION SYSTEM AND METHOD USING MONITORED OPERATING CONDITIONS OF A PROCESS CHAMBER	UESUGI, FUMIHIKO

09504435	6284049	150	02/15/2000	Processing APPARATUS FOR FABRICATING LSI DEVICES	UESUGI, FUMIHIKO
09656713	Not Issued	71	09/07/2000	Apparatus for monitoring particles and method of doing the same	UESUGI, FUMIHIKO
09685351	6423176	150	10/10/2000	PARTICLE-REMOVING APPARATUS FOR A SEMICONDUCTOR DEVICE MANUFACTURING APPARATUS AND METHOD OF REMOVING PARTICLES	UESUGI, FUMIHIKO
09721703	6737666	150	11/27/2000	APPARATUS AND METHOD FOR DETECTING AN END POINT OF A CLEANING PROCESS	UESUGI, FUMIHIKO
09767960	Not Issued	161	01/24/2001	Dust particle removing method and apparatus, impurity detecting method and system	UESUGI, FUMIHIKO
09950759	Not Issued	161	09/13/2001	Semiconductor fabrication device and method for preventing the attachment of extraneous particles	UESUGI, FUMIHIKO
09962169	Not Issued	161	09/24/2001	Semiconductor device manufacturing apparatus and method for manufacturing a semiconductor device	UESUGI, FUMIHIKO
09971463	Not Issued	83	10/05/2001	Particle-removing apparatus for a semiconductor device manufacturing apparatus and method of removing particles	UESUGI, FUMIHIKO
10166303	Not Issued	71	06/11/2002	Method of manufacturing semiconductor devices and semiconductor manufacturing apparatus	UESUGI, FUMIHIKO

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